

MICRO-503 MEMS practicals II

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| Cursus | Sem. | Type |
|---------------|----------|------|
| Microtechnics | MA2, MA4 | Opt. |

Language of **English** teaching Credits Withdrawal Unauthorized Summer Session Semester Spring During the Exam semester Workload 60h Weeks 14 Hours 2 weekly 2 weekly Number of positions It is not allowed to withdraw from this subject after the

registration deadline.

Summary

Objective of this practical is to apply in specific experimental settings the knowledge acquired in various MEMS related class

Content

The practical is organized in several lab experiments.

The part I (winter semester) is dedicated to MEMS technology and MEMS simulation:

- Finite element simulation of MEMS
- Design of MEMS actuators
- · Fabrication of MEMS actuators
- Caracterization of MEMS actuators
- Noise in sensors

The part 2 (spring smester) is dedicated to sensors:

- · capacitive accelerometer
- ISFET
- Glucose sensor
- piezoresistive pressure sensor Electrokinetic chip

Learning Outcomes

By the end of the course, the student must be able to:

- Conduct an experiment
- Report on experiments

Transversal skills

• Demonstrate the capacity for critical thinking

Teaching methods

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Practicals supervised by assistants

Assessment methods

Based on work in the lab, anwer to questions during experimental sessions and quality of the report

Supervision

Office hours Yes Assistants Yes

Resources

Moodle Link

• https://go.epfl.ch/MICRO-503

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